



MOCVD LAB IN ENGINEERING CENTERS BUILDING 16C1Y



Design-Bid-Build Single Prime

This project remodels suite 206d in the Engineering Centers Building for a new facility recruit involved in Metal Organic Chemical Vapor Deposition (MOCVD) used in the manufacturing of computer chips. It will be an H5 hazardous occupancy with intensive equipment needs.

BUDGET

Total	\$756,000
Construction	\$608,000
Design	\$60,800
Mgt.	\$27,000
Contingency	\$60,800
Equipment	\$0
Other Fees	\$0
Funding Sources:	
Gifts & Grants	\$756,000

TIMELINE

A/E Selection	04/2016
35% Design Report	05/2016 - 07/2016
Construction Documents	07/2016 - 08/2016
Bid Date	12/2016
Construction	02/2017 - 11/2017
Substantial Completion	11/2017
Occupancy	11/2017

KEY STAKEHOLDERS

Occupants	College of Engineering
User Reps	Sharon Devenish
UW PM	Pete Heaslett
DFD PM	Doug Schorr
A/E	KEE Architects
Design Arch.	N/A
Landscape Arch.	N/A
Structural Engr.	N/A
General Contractor	Miron Construction
Plumbing	Hooper Corp.
Mechanical	H&H
Fire Protection	Ahern
Electrical	Forward Electric

AREA DATA

GSF	N/A
ASF	N/A
Efficiency	N/A
Construction \$/GSF	N/A
Total Project \$/GSF	N/A